IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant:

Luetzen

Docket No.:

2004 SP 0115

Serial No.:

10/721,225

Art Unit:

1792

Filed:

11/26/2003

Examiner:

Goudreau

For:

Method and Structures for Increasing the Structure Density and the Storage

Capacitance in a Semiconductor Wafer

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

AFFIDAVIT FROM INVENTORS

Dear Sir:

I, Stephan Kudelka, hereby state that:

- 1. I am a joint inventor of the above-reference patent application.
- 2. I am the sole inventor of U.S. Patent No. 6,566,273 ("the '273 patent").
- 3. Any portions of the '273 patent that describe subject matter claimed in the above-referenced patent application was developed by me or learned by me from my co-inventors in the above-referenced patent application.

I each hereby declare that all statements made herein of my own knowledge are true and that all statements made on information and belief are believed to be true; and further that these statements were made with the knowledge that willful false statements and the like so made are punishable by fine or imprisonment, or both, under Section 1001 of Title 18 of the United States Code and that such willful false statements may jeopardize the validity of the application or any patent issued thereon.

Respectfully submitted,

Date

Stephan Kudelka

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Affidavit